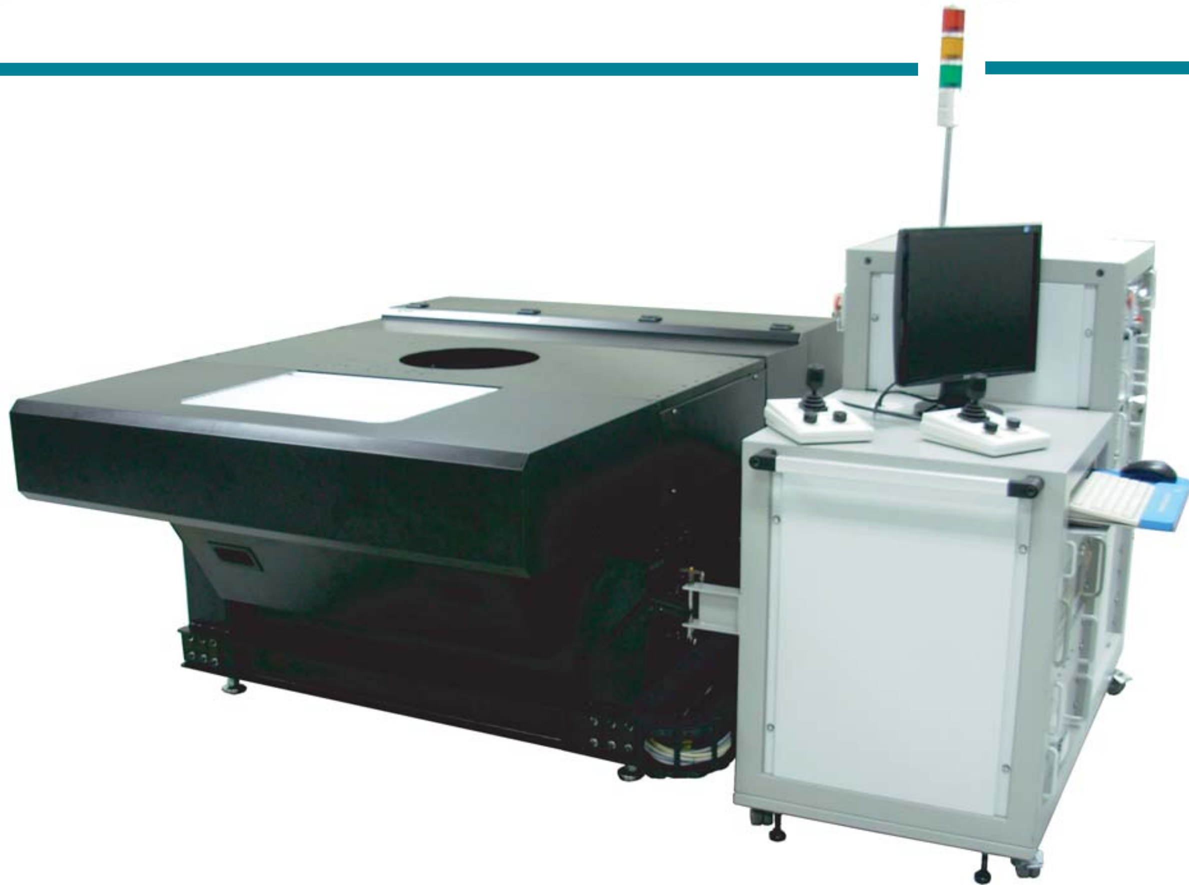
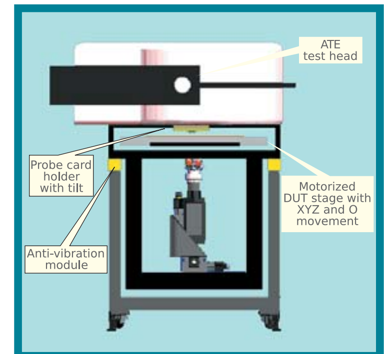
SEMICAPS 5000 CONFIGURATION

TESTER-DOCKED WAFER PROBER SYSTEM

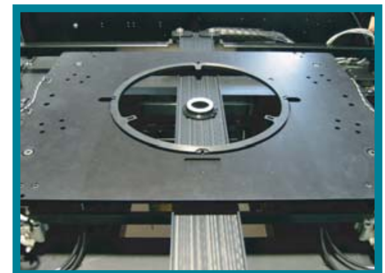


Features

- ATE direct docking using Production Probe Cards
- Patent pending wafer support allows RSIL imaging while docked to ATE
- Probe landing using optical registration
- High resolution stage with 20nm resolution and 0.5µm repeatability
- Centric and Aplanatic Refractive Solid Immersion Lens (RSIL) option
- CAD interface option
- Fully automatic die-to-die techniques include:
  - Laser Timing Probe (LTP) with frequency mapping for locating signals
  - Scanning Optical Microscopy (SOM) with best-in-class sensitivity for static and dynamic laser induced techniques
  - Photon Emission Microscopy (PEM) with LN2-free, low noise InGaAs or SI-CCD camera
  - Thermal Microscopy (THM) with InSb camera



ATE-Docked



Wafer Prober

SEMICAPS Pte Ltd
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SEMICAPS
Excellence In Innovation

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